



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:)
Yoshihiro MORI et al.) Group Art Unit: 2813
Serial No. 09/942,038) Examiner: Yen-nhu B. Huynh
Filed: August 30, 2001)
For: A METHOD FOR FABRICATING) Confirmation No. : 7302
SEMICONDUCTOR DEVICE INCLUDING)
ANNEALING LOWER ELECTRODE IN A)
REDUCING ATMOSPHERE BEFORE)
CAPACITOR INSULATING FILM FORMING)
(AS AMENDED))

CERTIFICATE OF MAILING OR TRANSMISSION

I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage for first class mail in an envelope addressed to: Mail Stop AF, Commissioner for Patents, P.O. Box 1450, Alexandria, Virginia 22313-1450, or being facsimile transmitted to the USPTO at (703) 872-9306, on January, 2004.

Angelique Graham

AMENDMENT AFTER FINAL OFFICE ACTION

Mail Stop AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In response to the final Office Action mailed October 22, 2003, please amend the above identified application as follows.

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